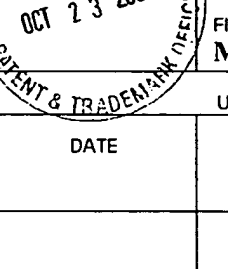
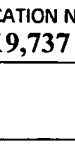
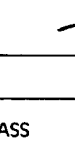
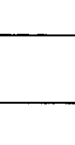
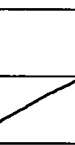
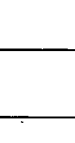



FORM PTO 1449 (modified) U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary) Date Submitted to PTO: October 23, 2001		ATTY DOCKET NO. 862.C2183		APPLICATION NO. 09/819,737	
APPLICANT Haruhiro ONO, et al.				FILING DATE March 29, 2001	
				GROUP 2812	



U.S. PATENT DOCUMENTS						
*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

FOREIGN PATENT DOCUMENTS						
DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT	

OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)	
	"Sub-Nanometer Miniature Electron Microscope", A.D. Feinerman, et al., Journal of Vacuum Science and Technology A, Vol. 10, No. 4, July/August 1992, 611-616.
	"High Aspect Ratio Aligned Multilayer Microstructure Fabrication", K. Y. Lee, et al., Journal of Vacuum Science and Technology B, Vol. 12, No. 6, November/December 1994, pp. 3425-3430.
	"Arrayed Miniature Electron Beam Columns For High Throughput Sub-100 nm Lithography", T. H. P. Chang, et al., Journal of Vacuum Science and Technology B, Vol. 10, No. 6, November/December 1992, pp. 2743-2748.
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EXAMINER 	DATE CONSIDERED 6-19-02
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U.S. DEPARTMENT OF COMMERCE

PATENT AND TRADEMARK OFFICE

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(Use several sheets if necessary)

Date Submitted to PTO: October 23, 2001

ATTY DOCKET NO.

862.C2183

APPLICATION NO.

09/819,737

APPLICANT

Haruhiro ONO, et al.

FILING DATE

March 29, 2001

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*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
<i>[Signature]</i>	5,834,783	11/10/1998	Muraki, et al.	250	398	
	5,864,142	01/26/1999	Muraki, et al.	250	491.1	
	5,905,267	05/18/1999	Muraki	250	492.22	
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	6,107,636	08/22/2000	Muraki	250	492.2	
	6,104,035	08/15/2000	Muraki	250	492.22	
	6,166,387	12/26/2000	Muraki, et al.	250	492.2	
	5,929,454	07/27/1999	Muraki, et al.	250	491.1	
	5,939,725	08/17/1999	Muraki	250	492.22	
	5,973,332	10/26/1999	Muraki, et al.	250	492.2	
	6,137,113	10/24/2000	Muraki	250	492.22	
<i>[Signature]</i>	4,419,580	12/06/1983	Walker, et al.	250	396 R	

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OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)

EXAMINER

DATE CONSIDERED

6/19/02

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered.

Include copy of this form with next communication to applicant.

Sheet 1 of 2